

# Performing Charge Pumping Measurements with the Model 4200-SCS Semiconductor Characterization System

## Introduction

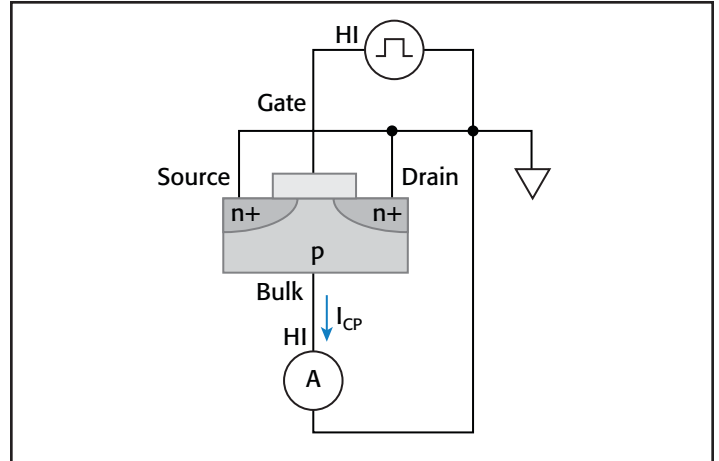
Charge pumping (CP) is a well-known measurement technique for analyzing the semiconductor–dielectric interface of MOS structures. Important information about the quality and degradation of a device can be extracted from charge pumping current ( $I_{CP}$ ) measurement results, including the interface trap density and the mean capture cross section. Pulsing a gate voltage and measuring a DC substrate current simultaneously is the basis for the various charge pumping methods, so a pulse generator and sensitive DC ammeter are required to make these measurements.

The Model 4200-SCS Semiconductor Characterization System offers a complete solution for charge pumping measurements because it contains the necessary hardware to make the sensitive measurements, as well as software to automate the measurements and analyze the results. This system is provided with predefined tests for making most of the common charge pumping tests, such as a pulsed base voltage sweep or a pulsed voltage amplitude sweep. This application note explains how to make charge pumping measurements using the Model 4200-SCS with the optional Model 4225-PMU Ultra Fast I-V Module (PMU) or Model 4220-PGU Pulse Generator Unit (PGU).

## Charge Pumping Overview

**Figure 1** is a charge pumping measurement circuit diagram. Basically, the gate of the MOSFET is connected to a pulse generator, which repeatedly switches the transistor from accumulation to inversion. While the gate is pulsed, a recombination process of majority/minority carriers occurs on the rising and falling edges of the pulses. This causes a current to flow in the opposite direction of the normal drain-to-source current. This induced current is known as the charge pumping current ( $I_{CP}$ ) and can be measured by connecting a sensitive ammeter to the substrate, or bulk terminal, of the MOSFET.

Although several charge pumping methods have been developed, the basic charge pumping technique involves measuring the substrate current while applying voltage pulses of fixed amplitude, rise time, and frequency to the gate of the transistor. The source and drain are either tied to ground or slightly reverse-biased. The voltage pulse can be applied with a fixed amplitude while sweeping the base voltage or with a fixed base voltage while sweeping the amplitude of the pulse.



**Figure 1. Basic charge pumping measurement circuit**

In the fixed-amplitude/voltage-base sweep, the amplitude and period (width) of the pulse are kept constant while the base voltage is swept from inversion to accumulation. This waveform and the corresponding curve of the charge pumping current shown as a function of the base voltage are both illustrated in **Figure 2**. From the data, it's possible to extract the interface trap density ( $N_{it}$ ) using this equation:

$$N_{it} = \frac{I_{CP}}{qfA}$$

where:

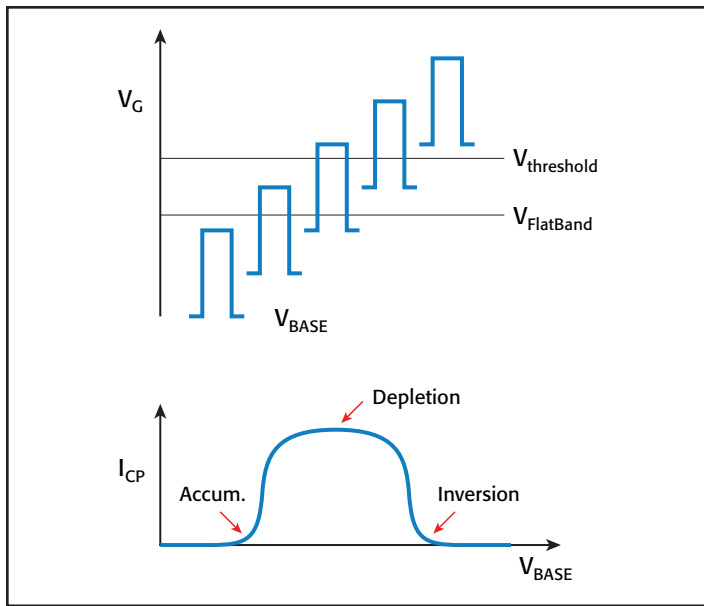
- $N_{it}$  = interface trap charge density ( $\text{cm}^{-2}$ )
- $I_{CP}$  = charge pumping current (A)
- $f$  = test frequency (Hz)
- $q$  = electron charge,  $1.6022 \times 10^{-19}$  C
- $A$  = channel area ( $\text{cm}^2$ )

The interface trap density as a function of band bending can also be extracted from the following equation:

$$D_{it} = \frac{I_{CP}}{qf\Delta E}$$

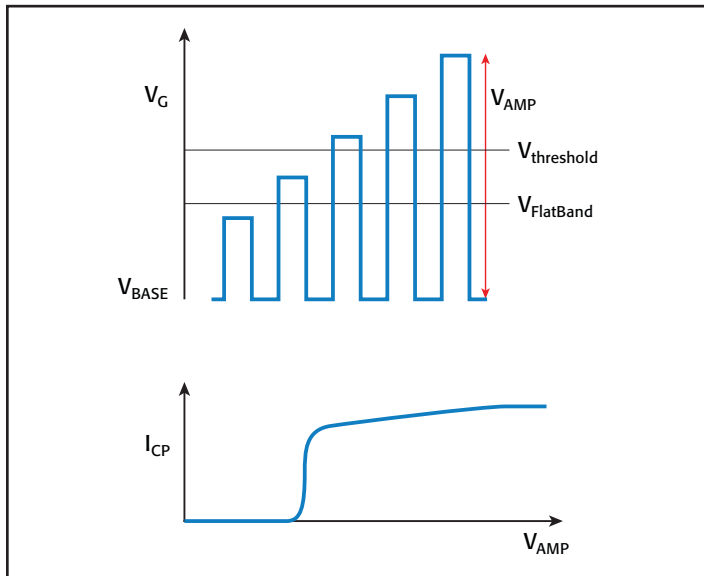
where:

- $D_{it}$  = interface trap charge density ( $\text{cm}^{-2}\text{eV}^{-1}$ )
- $I_{CP}$  = charge pumping current (A)
- $f$  = test frequency (Hz)
- $q$  = electron charge,  $1.6022 \times 10^{-19}$  C
- $A$  = channel area ( $\text{cm}^2$ )
- $\Delta E$  = the difference between the inversion Fermi level and the accumulation Fermi level [1]



**Figure 2. Pulse waveform for fixed-amplitude/voltage-base sweep and corresponding charge pumping current curve**

The fixed-base/variable-amplitude sweep method is another common technique for determining the charge pumping current. With this method, the base voltage is kept constant in accumulation and the variable voltage amplitude is pulsed into inversion. As shown in **Figure 3**, as the voltage amplitude ( $V_{AMP}$ ) of the pulses increases, the charge pumping current saturates and stays saturated.



**Figure 3. Pulse waveform for fixed-base/variable-amplitude sweep with corresponding charge pumping current curve**

Other charge pumping techniques are used in addition to the fixed-amplitude/variable-base sweep and the fixed-base/variable-amplitude sweep. In some cases, the voltage waveform can have various shapes, the rise and fall times can be varied, or the charge pumping current can be measured as a function of frequency.

## Hardware Configuration

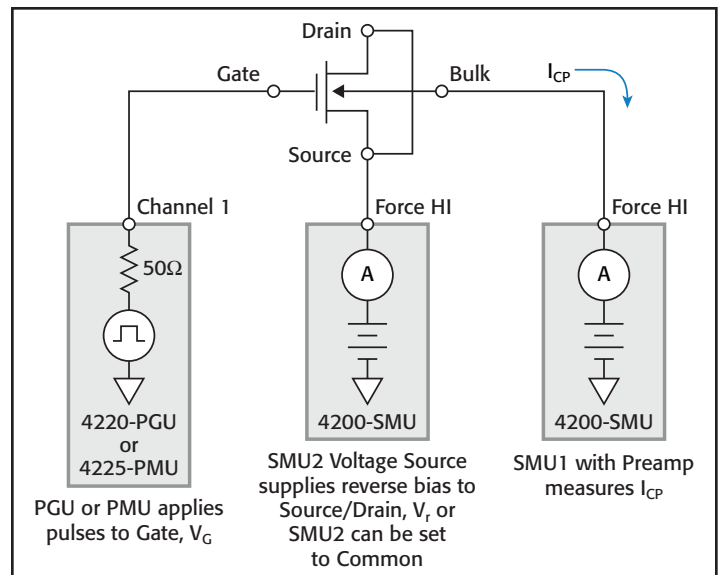
**Figure 4** is the basic circuit diagram for making charge pumping measurements using the Model 4200-SCS. For this application, the Model 4200-SCS is configured with either a Model 4220-PGU Pulse Generator Unit (PGU) or a Model 4225-PMU Ultra Fast I-V Module (PMU), one or two Model 4200-SMU Source Measure Units (SMU), and one Model 4200-PA Preamp.

The pulser (4225-PMU or 4220-PGU) is connected to the gate of the MOSFET in order to apply pulses of sufficient amplitude to drive the device between inversion and accumulation. Depending on the charge pumping method, the PGU or PMU can sweep the pulse amplitude, sweep the base voltage, vary the rise/fall time, and vary the test frequency. The test frequency is usually in the kilohertz to megahertz range.

SMU1 is connected to the Bulk terminal and measures the resulting substrate current. This charge pumping current ( $I_{CP}$ ) is often in the nanoamp or picoamp range. For measuring currents of less than one nanoamp, the optional Model 4200-PA should be used.

The source and drain terminals of the MOSFET are tied together and connected to SMU2, which applies a slight reverse bias ( $V_r$ ). If  $V_r = 0$ , then the source/drain terminals can be connected to the ground unit (GNDU) instead of to SMU2. To prevent oscillations and minimize noise, it is very important to connect the LO (common) terminals of all the SMUs and the pulser (4225-PMU or 4220-PGU) as close as possible to the device. The LO terminal of the SMU is the outside shell of the triax connector. The LO terminal of the PMU and PGU is the outside shield of the SMA cable.

To minimize noise in low current measurements due to electrostatic interference, make sure the device is shielded by placing it in a metal enclosure with the shield connected to the LO terminal of the SMU. Further information on making low



**Figure 4. Model 4200-SCS configuration for charge pumping measurements**

current measurements with the Model 4200-SCS is available in Keithley Application Note Number 2959, “Optimizing Low Current Measurements with the Model 4200-SCS Semiconductor Characterization System.”

## Using the KITE Software to Automate the Charge Pumping Measurements

The Model 4200-SCS comes with a project that contains a library of tests used in many of the common charge pumping measurement techniques. This *chargepumping* project is located

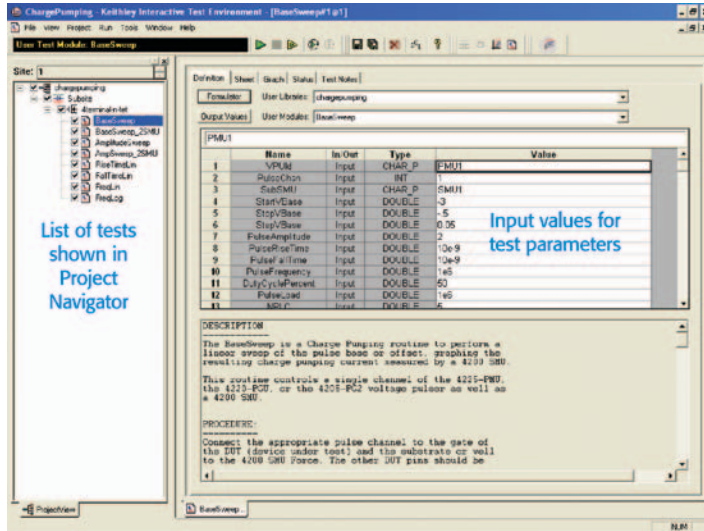


Figure 5. The *chargepumping* project

Table 1. Charge pumping user test modules

User Test Modules	Description
<i>BaseSweep</i>	The base voltage of the waveform is swept while the amplitude of the pulse is kept constant. The resulting charge pumping current is measured and graphed as a function of the base voltage. The source/drain terminals are tied to ground.
<i>BaseSweep_2SMU</i>	Same as <i>BaseSweep</i> test, except it adds a second SMU to apply a DC voltage bias to the source/drain terminals.
<i>AmplitudeSweep</i>	The amplitude of the pulse is swept while the base voltage is kept constant. The charge pumping current is measured and graphed as a function of the pulse amplitude voltage. The source/drain terminals are tied to ground.
<i>AmplitudeSweep_2SMU</i>	Same as <i>AmplitudeSweep</i> test, except it adds a second SMU to apply a DC voltage bias to the source/drain terminals.
<i>RiseTimeLin</i>	Performs a linear sweep of the rising transition time of the pulse. $I_{CP}$ is measured and graphed as a function of the rise time. The source/drain terminals are tied to ground.
<i>FallTimeLin</i>	Performs a linear sweep of the falling transition time of the pulse. $I_{CP}$ is measured and graphed as a function of the fall time. The source/drain terminals are tied to ground.
<i>FreqLin</i>	With the amplitude, offset voltage, rise/fall times constant, the $I_{CP}$ is measured as a function of a linear sweep of the test frequency. The source/drain terminals are tied to ground.
<i>FreqLog</i>	With the amplitude, offset voltage, and rise/fall times constant, the $I_{CP}$ is measured and graphed as a function of a log sweep of the test frequency. The source/drain terminals are tied to ground.

in the projects folder: *C:\S4200\kiuser\Projects\\_Pulse*. When this project is opened, a list of the tests is displayed in the Project Navigator (Figure 5). Table 1 lists the user test modules (UTMs) included in the project and a brief description of each test.

The user selects the desired test and then inputs the appropriate values for the test parameters on the Definition Tab. The parameters vary depending on the particular test, but they usually include the magnitude of the pulse, sweep values, rise/fall time, test frequency, duty cycle, etc. Specific information on these tests, including the test parameters, is available in Section 16 of the Model 4200-SCS Complete Reference Manual.

After the hardware and the software have been configured, the measurement can be executed in the project by clicking the on-screen Run button. The measurements are displayed in the Graph tab and listed in the Sheet tab. The Sheet tab is used to record and manipulate the data. The measurements ( $I_{CP}$ ,  $Q_{CP}$ , pulsed voltage, etc.) can be saved in a worksheet as an .xls, .txt, or .csv file.

The graph from executing the *BaseSweep* user test module is shown in Figure 6. This user test module measures the charge pumping current as a function of the base voltage.

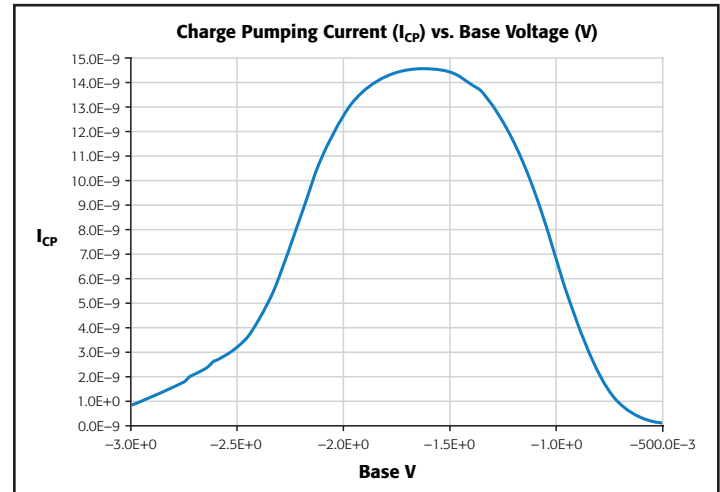


Figure 6. Graphical results of *BaseSweep* user test module

The input parameter values of a user test module can be updated and the measurements can be repeated. One way to do this is by using the on-screen Append Run button, which can be used to show multiple test results on one graph. Figure 7 shows the test results of increasing the test frequency from 1MHz to 6MHz. The data is appended to the graph and a new worksheet is added in the Sheet tab for each appended test run.

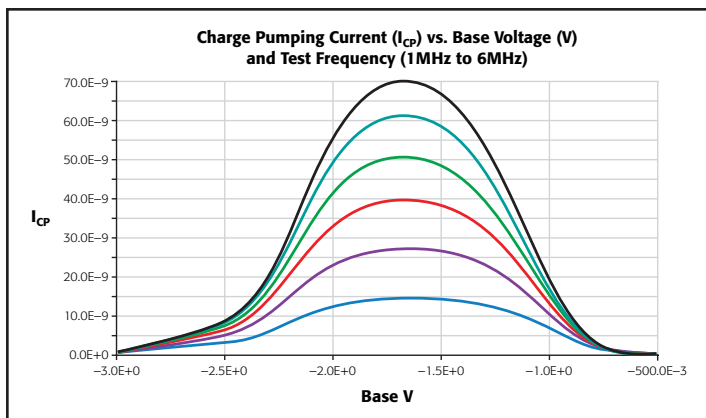


Figure 7. Charge pumping current measurement results at multiple test frequencies

The *AmplitudeSweep* is another common charge pumping test. It measures the charge pumping current as the amplitude of the pulse is swept. The base voltage is kept constant. The resulting charge pumping measurements are shown in *Figure 8*.

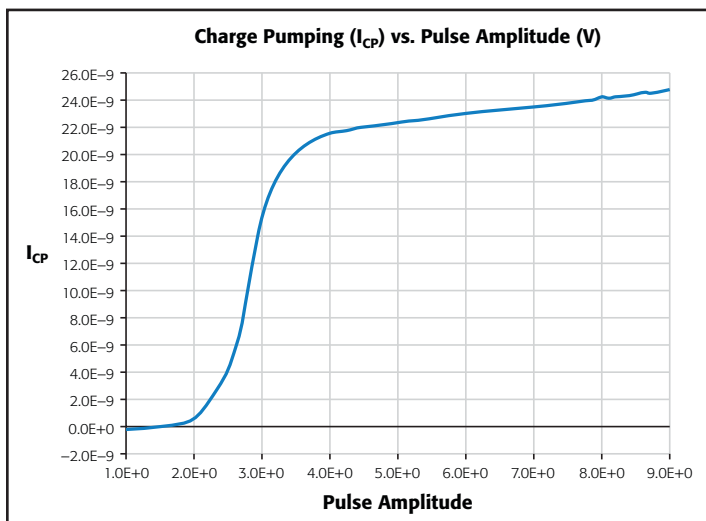


Figure 8. Charge pumping current as a function of pulse amplitude

Simple analyses, such as extracting the interface trap density, can be performed on the data using the built-in Formulator

function. To activate this function, click the Formulator button on the Definition tab of the test setup window. Enter the formula for  $D_{it}$  as shown in *Figure 9*. The resulting  $D_{it}$  value can also be plotted in the graph.

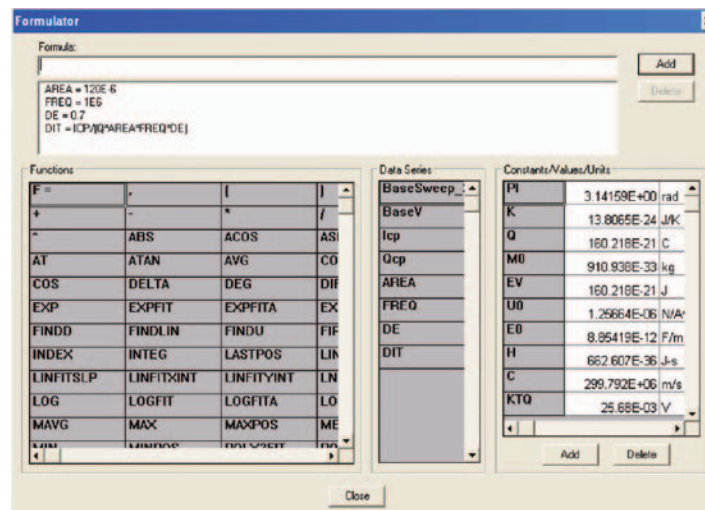


Figure 9. Entering formulas in the Formulator function

## Conclusion

The Model 4200-SCS is the ideal tool for characterizing interface properties of gate dielectrics. With the built-in pulse generator, Model 4225-PMU or Model 4220-PGU, and the KTE Interface software, the user need not do any programming, which simplifies measurement and analysis. When equipped with the Model 4225-PMU, the Model 4200-SCS is a powerful tool for performing many tests commonly required in DC and ultra-fast I-V electrical characterization of devices, including the charge pumping application detailed here. The 4225-PMU is not simply a pulse generator; it can also measure current and voltage and be used for transient I-V (waveform capture) applications.

## References

1. G. Groeseneken, H.E. Maes, N. Beltran, and R.T. De Keersmaecker, "A Reliable Approach to Charge-Pumping Measurements in MOS Transistors," *IEEE Trans. Electron. Dev.*, Vol. ED-31, pp. 42-53, 1984.

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